Title (en)

## SUBSTRATE TURNING DEVICE

Title (de)

SUBSTRATWENDEEINRICHTUNG

Title (fr)

DISPOSITIF DE RETOURNEMENT DE SUBSTRATS

Publication

## EP 2764536 A1 20140813 (DE)

Application EP 11779222 A 20111006

Priority

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Abstract (en)

[origin: WO2013050805A1] The invention relates to a substrate turning device for a substrate processing system for processing plate-shaped substrates, wherein the substrate processing system is a pass-through system having at least two process chambers and at least one separating chamber between the process chambers and has at least one substrate carrier that can be moved through the pass-through system in at least one transport direction for the substrates, said substrate carrier having several frame-shaped, internally open carrier cells arranged one next to the other and/or one after the other in a horizontal plane for supporting one substrate each at substrate edge areas. The aim of the invention is to provide a substrate turning device of the stated type by means of which the substrates can be turned while the substrates pass through the substrate processing system on a substrate carrier, wherein the energy requirement for the turning of the substrates is as low as possible and the substrates can be optimally processed. Furthermore, it should be possible to provide the substrate processing system with the smallest possible footprint and low production costs. The aim is achieved by a substrate turning device of the stated type, wherein at least one turning station is provided in the separating chamber, at which turning station a vertically movable or extendable substrate turning mechanism having retaining elements that can be moved relative to each other for retaining the substrates at two opposite substrate edge areas is provided above the substrate cells, wherein the retaining elements or rotational axes of the retaining elements are connected in the form of a frame by connecting elements provided perpendicular to the retaining elements or the rotational axes and the frame can be rotated by at least 180° about the horizontal center axis of the frame.

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